



Docket No.: 0941-0938PUS1  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re Patent Application of:  
Hung-Wen SU et al.

Application No.: 10/810,619

Confirmation No.: 009827

Filed: March 29, 2004

Art Unit: 1763

For: APPARATUS AND METHOD FOR  
REMOVING METAL FROM WAFER EDGE

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Examiner: S. MacArthur

**FIRST PRELIMINARY AMENDMENT**

MS RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**INTRODUCTORY COMMENTS**

Further to the Request for Continued Examination (RCE) being filed concurrently herewith, and in response to the Final Office Action dated November 16, 2005, the following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

This reply includes:

Amendments to the Claims; and

Remarks.